

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: NAKATA, Yoshihiro et al.

Group Art Unit: 1771

Serial No.: 10/807,174

Examiner: Hai VO

Filed: March 24, 2004

P.T.O. Confirmation No.: 4205

FOR: SILICON-BASED COMPOSITION, LOW DIELECTRIC CONSTANT FILM,

SEMICONDUCTOR DEVICE, AND METHOD FOR PRODUCING LOW

DIELECTRIC CONSTANT FILM

## AMENDMENT ACCOMPANYING REQUEST FOR CONTINUED EXAMINATION

## **MAILSTOP RCE**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

October 29, 2007

Sir:

In response to the Office Action dated June 4, 2007, please amend the above-identified application as follows. A Request for Continued Examination (RCE) and a Petition for Extension of time are concurrently filed herewith.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.